## Supplementary Information

#### Solid Phase Crystallization of Amorphous Silicon at the Two-

#### **Dimensional Limit**

Daya S. Dhungana<sup>1</sup>, Eleonora Bonaventura<sup>1</sup>, Christian Martella<sup>1</sup>, Carlo Grazianetti<sup>1\*</sup>, Alessandro Molle<sup>1\*</sup>

<sup>1</sup> CNR-IMM Agrate Brianza Unit, via C. Olivetti 2, Agrate Brianza, I-20864, Italy

\*Corresponding authors: <a href="mailto:carlo.grazianetti@mdm.imm.cnr.it">carlo.grazianetti@mdm.imm.cnr.it</a>, <a href="mailto:alessandro.molle@mdm.imm.cnr.it">alessandro.molle@mdm.imm.cnr.it</a>,

KEYWORDS: Silicene, Solid Phase Crystallization, Molecular Beam Epitaxy, 2D Materials

#### SI1: Auger Spectra

S12: LEED Patterns below 1 Monolayer

SI3: Methodology for Nominal Thickness

SI4: Region of Interest with Si Pixels Merger

S15: Raman Analysis of Region of Interest

### SI1: Auger Spectra of sample after 400 °C Annealing



**Figure S1:** Auger spectra acquired on two different surfaces: (i) black before depositing Si (ref. main text **figure 1a**) and (ii) red after annealing deposited Si at 400 °C (main text **figure 1f**).

### SI2: LEED Patterns below 1 Monolayer



Ag:1x1

Amorphous-Si (0.5 Monolayer) Post Growth Annealing (300 °C)

**Figure S2:** (a) Ag:1x1 surface post to preparation. (b) Amorphous-Si after depositing 0.5 monolayer of Si on Ag(111). (c) LEED patterns observed after heating surface in (b) at 300 °C for 15 minutes. Incident LEED Energies ( $E_i$ ) for (a), (b) and (c) respectively are 90, 50 and 50 eV.

## SI3: Methodology for Nominal Thickness



**Figure S3:** Methodology to determine nominal crystalline length with the help of manipulator. The manipulator is moved along in one axis at a time, either x or y (z is perpendicular to the sample surface) until amorphous region (green) appears at the end. This gives the crystalline length.

# SI4: Region of Interest with Si-Pixels Merger

Region of Interest (ROI): Merger of several 2D crystalline-Si pixels

Figure S4: 3D sketch of Region of Interest (ROI) that was created on Amorphous-Si layers



Figure S5a: Raman measurements while moving towards amorphous-Si side from crystalline-Si side.



**Figure S5b:** Raman spectra at different positions between crystalline and amorphous-Si interface at Region of interest (**figure S4**). (D=-50  $\mu$ m; purple), (D=-100  $\mu$ m; orange), (D=-150  $\mu$ m; magenta) and (D=-200  $\mu$ m; black). Crf: **Figure 5** (main text)



**Figure S5c**: As acquired Raman spectra along a scan while moving from crystalline (left) to amorphous region (right) at Region of Interest (**figure S4**). Crf. **Figure 5** (main text).